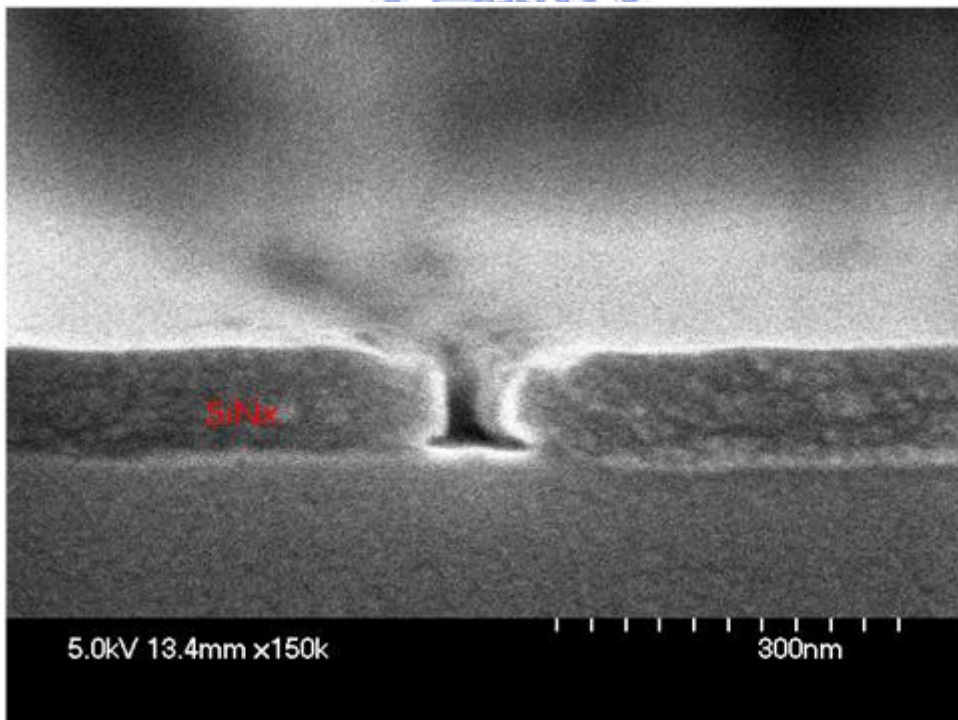
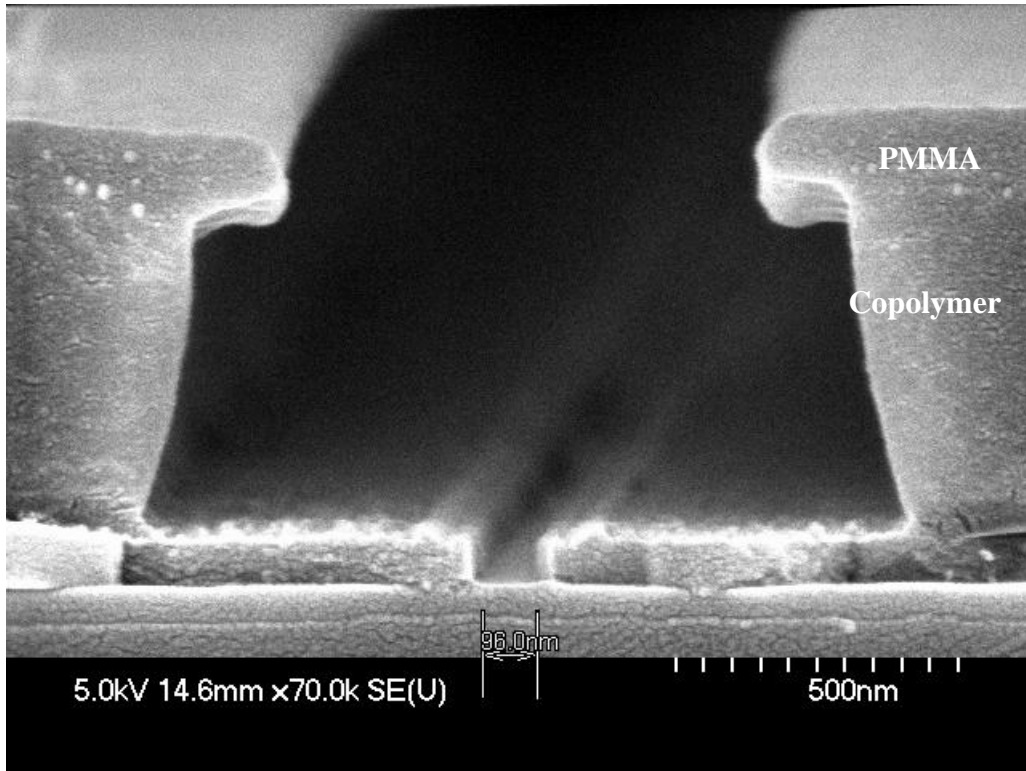


(c)  $\text{SiO}_2$  re-deposition

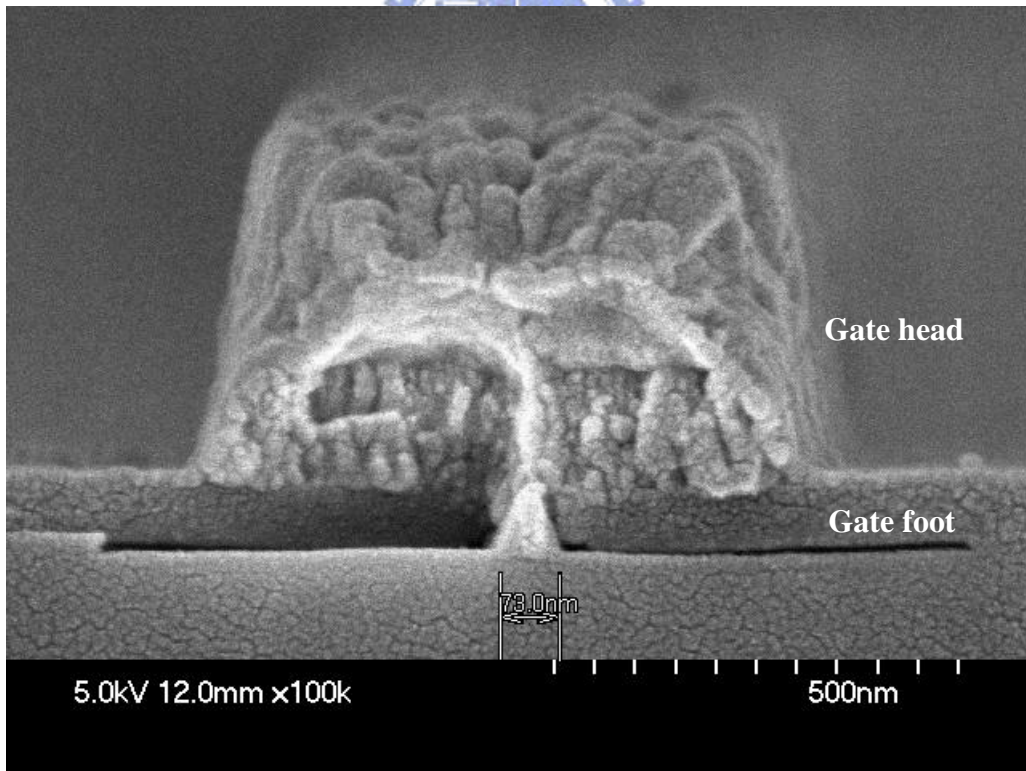


(d) over-etch

Fig. 3.6 SEM photos of the sidewall gate process (2)



(a) Before gate metal deposited



(b) After gate metal deposited

Fig. 3.7 SEM photos of the sidewall T-shaped gate before and after gate metal deposition

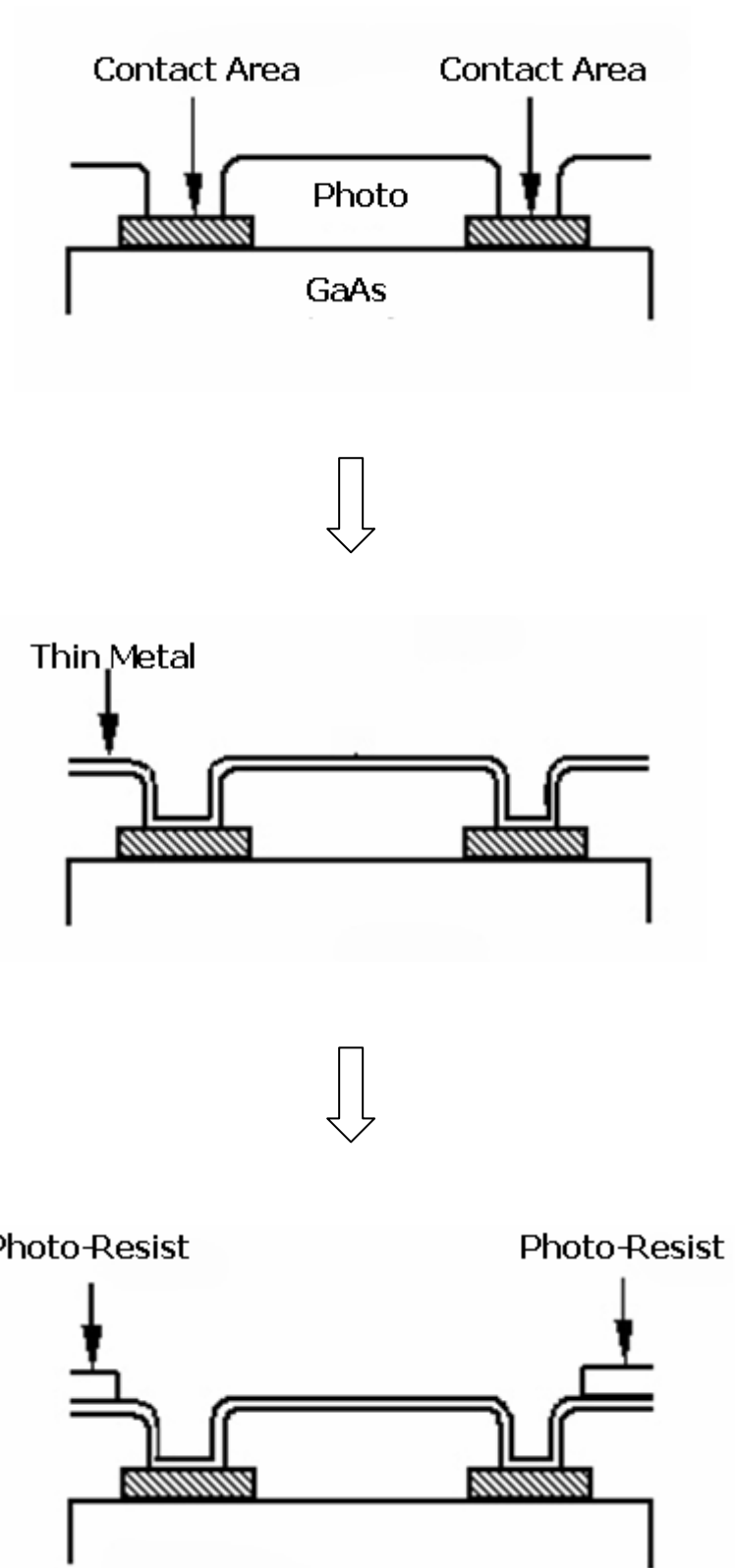


Fig. 3.8 Process flow of airbridge (1)

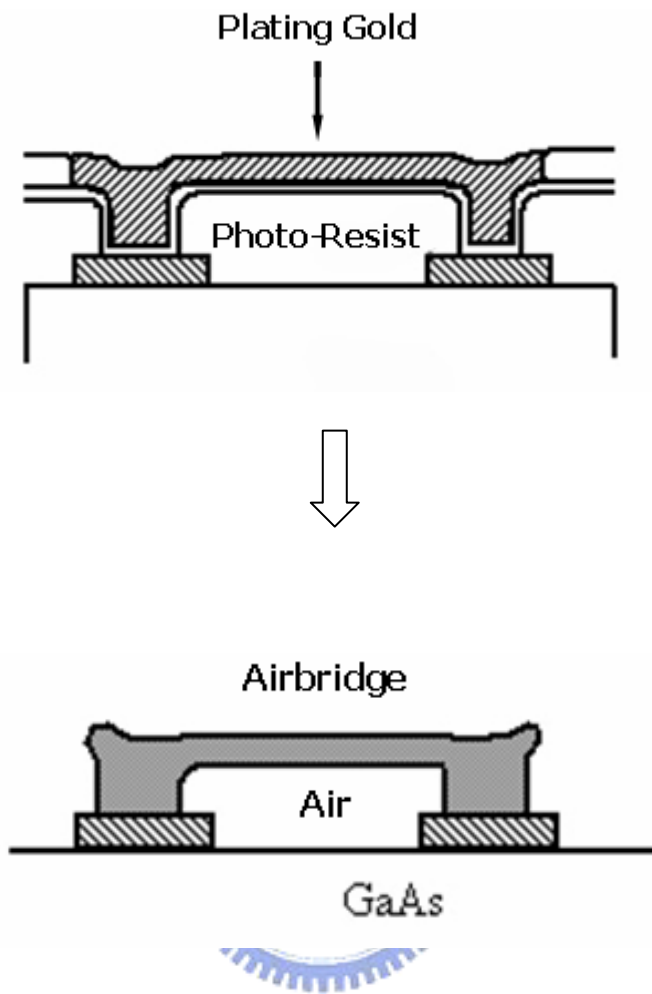


Fig. 3.8 Process flow of airbridge (2)